

Electronic Patent Application Fee Transmittal				
Application Number:	10581256			
Filing Date:	31-May-2006			
Title of Invention:	Plasma etching method			
First Named Inventor/Applicant Name:	Mitsuhiro Okune			
Filer:	Jeffrey John Howell/Emily English			
Attorney Docket Number:	2006_0772A			
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Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
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Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
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Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Request for continued examination	1801	1	810	810
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